

<b>Search Notes</b> 	<b>Application/Control No.</b> 10/693,898	<b>Applicant(s)/Patent under Reexamination</b> CHI, LI-WEN
	<b>Examiner</b> Richard K. Lee	<b>Art Unit</b> 2832

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
PGPUBS	print-out	8/20/2006	KL